

# Contact Resistivity of Evaporated Al Contacts for Silicon Solar Cells

Kean Chern Fong, Teng Choon Kho, Andreas Fell, Evan Franklin, Ngwe Zin, Andrew W. Blakers, Keith R. McIntosh, Thomas Ratcliff, Matthew Stocks, James Bullock and Er-Chien Wang.

**Abstract**—The contact resistivity of evaporated Al on doped silicon is examined for a range of process conditions common to the fabrication of laboratory silicon solar cells. The effects of silicon surface preparation prior to evaporation, sintering temperature, the use of a shutter, and evaporation power are investigated. The presented evaporation conditions yielded the lowest published contact resistivity between Al and phosphorus doped Si over a large range of doping concentration. It is also demonstrated that a contact resistivity below  $10^{-6} \Omega\text{-cm}^2$  can be achieved without sintering. Three-dimensional simulations are utilized to compare the obtained results for evaporated Al contacts with those for passivated contacts.

**Index Terms**— Photovoltaic cells, silicon solar cells, contact resistance, metal contacts, simulation

## I. INTRODUCTION

The use of evaporated Al is common in high-efficiency laboratory solar cells due to its properties of having low contact resistivity, high reflectivity, enhanced passivation of oxide-coated surfaces via annealing [1, 2], compatible with laser patterning and photolithographic patterning. It has been used as the metal contact interface in both n- and p-type high efficiency silicon solar cells [3-6].

Evaporated Al has not been adopted in cell manufacturing due to its high costs and low throughput but it could potentially be viable with the advancement of in-line evaporator systems [7].

It is generally observed that at a given doping concentration, the contact resistivity of phosphorus doped

contacts is approximately 2-3 orders magnitude higher than that of boron doped contacts, attributable to a higher barrier height at the contact interface for n-type silicon.

A sintering step at a temperature between 300-500 °C is often included in Al-evaporated contacts to form intimate contact [7-9]. The sintering step is undesirable for multiple reasons: it incurs an additional processing time and cost; it requires underlying dielectric films to be compatible in maintaining electrical isolation and passivation after sintering; it increases the possibility of contaminating the silicon; and it can cause non-ideal recombination or p-n junction shunting introduced by Al spiking into the silicon [9], adversely impacting the open-circuit voltage  $V_{OC}$  and fill factor  $FF$  of finished devices [10].

In this work, we present a thorough investigation of the correlation between contact resistivity and the process conditions, such as the evaporation rate, sintering temperatures, and sample surface doping concentration.

The characteristics of Si/Al contacts (both n+ and p+ doped Si) are then compared against literature values for passivated contacts via 3D simulations to demonstrate the idealised efficiency of each contacting technology in regards to solar cell efficiency.

## II. EXPERIMENTAL DETAILS

The test structures are fabricated using four-inch mechanically polished monocrystalline, (100) orientation, p-type, Czochralski (Cz), 100  $\Omega\text{-cm}$  wafers. The diffusion was performed using a high temperature quartz furnace tube with  $\text{POCl}_3$  vapour as the dopant source with a 2 hour 1000 °C furnace anneal drive-in step. The samples were then etched back to provide a range of surface concentrations, which were determined by measuring the diffusion profile using electrochemical capacitance-voltage (ECV) measurements. For the samples that were not measured directly by ECV, the dopant profile was assumed to be identical with that measured for the non-etched sample but neglecting the first  $x$   $\mu\text{m}$  of the profile. The depth  $x$  is selected such that the calculated sheet resistance of the profile equaled the measured sheet resistance of the sample. The measured and calculated profiles are plotted in Fig. 1.

The samples were given a dip in 5% hydrofluoric acid and blown dry immediately prior to metal evaporation. Metal evaporation was performed in a vacuum bell jar, using a disposable tungsten boat loaded with Al pellets (5N purity). The vacuum jar is evacuated to  $5 \times 10^{-5}$  Torr using an oil vacuum roughing pump and a cryopump with precautions to prevent back streaming of oil into the chamber via

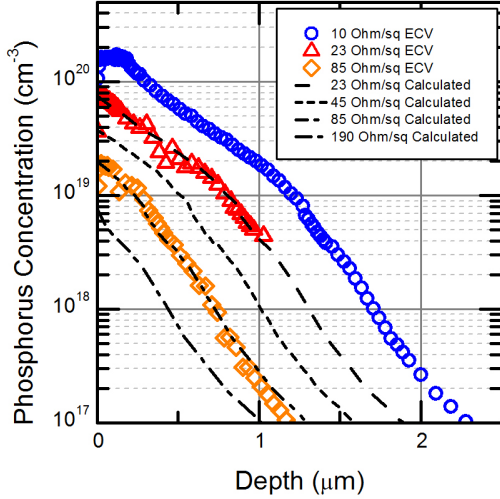
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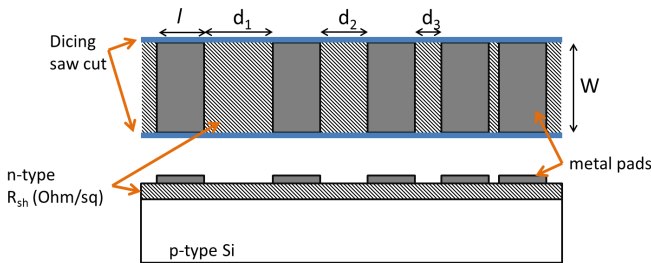
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electronically controlled valves. The deposition rate is measured using a gold coated crystal (6MHz by Inficon). The boat power is varied between 600 W and 800 W for the evaporation step which corresponds to a deposition rate of 10 Å/s to 60 Å/s respectively and evaporation is stopped when the Al source is depleted, determined by the deposition rate dropping below 3 Å/s. The thickness of evaporated Al on the samples is approximately 1 μm.



**Figure 1:** Doping profile of samples after etch-back. Comparison between measured profiles and profiles calculated from sheet resistance shows good agreement.

The contact between metal and semiconductor is characterised by its contact resistivity  $\rho_c$  ( $\Omega \cdot \text{cm}^2$ ) measured by the transmission line method (TLM) [9, 11]. The TLM structure used is illustrated in Fig. 2, with pad length,  $l$  measuring 2 mm, width,  $W$  measuring 6 mm and gap spacing ( $d_x$ ) ranges from 13 μm to 303 μm. The structures are formed by standard photolithography followed by an etch using a metal etch solution consisting of  $\text{H}_3\text{PO}_4:\text{H}_2\text{O}:\text{HNO}_3$  at a ratio of 20:4:1. Individual TLM sets are physically cut out by dicing saw. A Keithley 2425 sourcemeter was used to perform 4 point measurement to eliminate systemic error of including the contact resistance between the probe and Al pad in the resistance measurements.

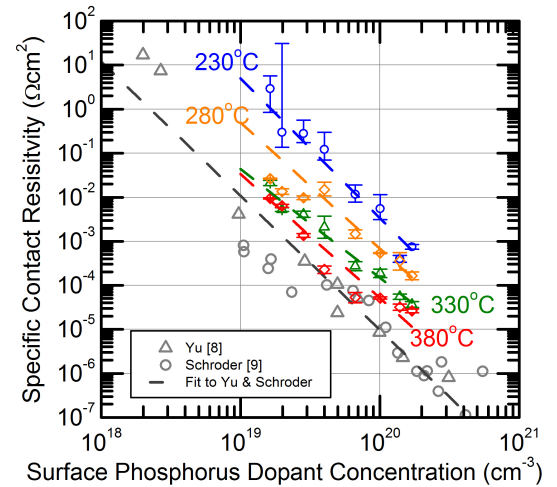


**Figure 2:** Illustration of TLM structure used.

### III. RESULTS AND DISCUSSION

We investigated the effect of sintering temperature using a baseline evaporation recipe with the shutter opened during the

Al pellet melting phase and using a boat power of 600 W, providing a maximum deposition rate of 10 Å/s. A set of samples were prepared as described in Section II and then sintered at temperatures ranging from 230 °C to 380 °C for 30 minutes in forming gas (FGA) (5% hydrogen 95% nitrogen). The results are presented in Fig. 3. The results published by Schroder [9] and Yu [8], which were attained by depositing Al with an electron beam gun and annealing between 400-500 °C, are also included for comparison. The contact resistivity prior to sintering is too high to be measured reliably with TLM, and is excluded from the data. Compared to the samples sintered at 380 °C, the contact resistivity for samples sintered at 230 °C is two orders of magnitude higher, and the contact resistivity for samples sintered at 280 °C is one order of magnitude higher.



**Figure 3:** Contact resistivity results for 600 W boat power with shutter always opened. Sintering was performed at designated temperature for 30 minutes.

It was observed that while it takes ~10 seconds for the tungsten boat to glow red, the pellets require a significant amount of time to melt and deposition to be detectable by the crystal sensor; specifically, it took 90 s, 45 s, and 35 s for boat powers of 600 W, 700 W and 800 W, respectively.

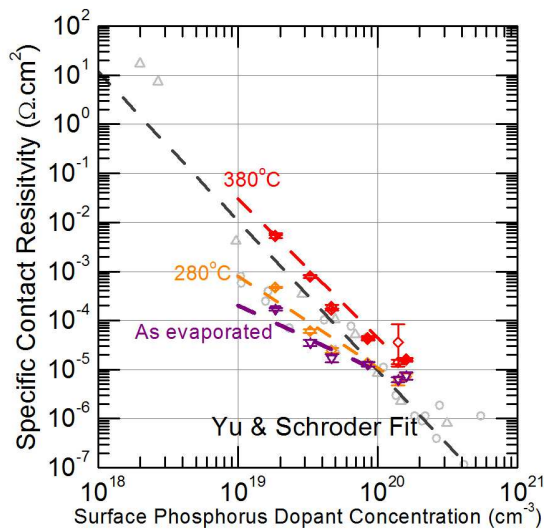
By keeping the evaporation shutter open, it is possible that contaminating substances from the exposed tungsten boat or surface contaminants from the Al metal are deposited onto the silicon samples prior to the Al pellets evaporating, forming an interfacial layer at the metal-silicon interface. To protect the samples from contaminants during this initial warm-up phase, the evaporation recipe was modified to keep the shutter closed until the Al pellets start to evaporate. Two sets of diffused samples were prepared and metal evaporation was performed at 600 W and 800 W. The sample preparation method is as described in Section II, and sintering was performed between 230 °C and 380 °C for 30 minutes in a FGA ambient. TLM measurements were performed before and after the sintering step.

The results are presented in Figs. 4 and 5. For both 600 W and 800 W, the lowest contact resistivity occurs when there is no sintering. Contact resistivity with no sintering, and at

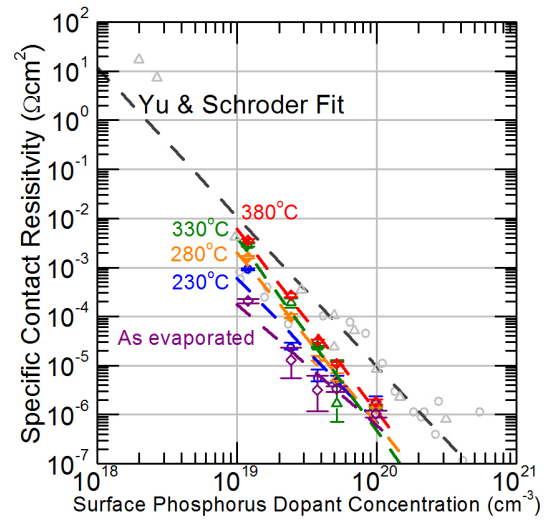
higher doping concentration is significantly lower when a higher boat power is used. The contact resistivity becomes higher when the samples are subjected to sintering, but does not exceed the values measured in Fig. 3. The reason for having lowest contact resistivity without sintering is unknown, but a possible explanation is that the contact resistivity between Si and Al is lower than the contact resistivity between Si and Si/Al alloy which forms as the interfacial layer when sintered even below the eutectic temperature.

The temperature of the samples during metal evaporation was determined to have not exceeded 80°C by direct evaporation of Al onto temperature sensitive strips with permanent color indicators.

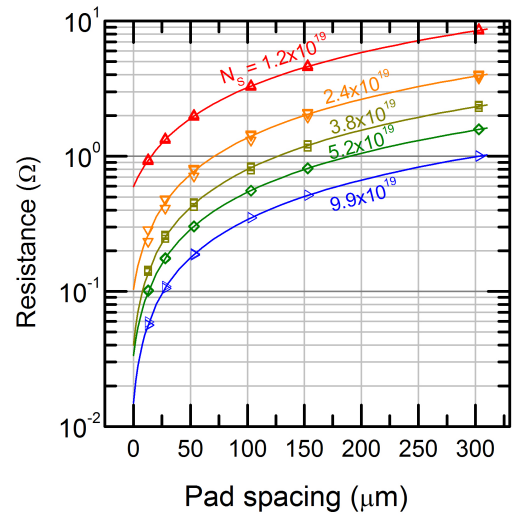
The measured contact resistivity for the unsintered samples with Al deposition power of 800 W is the lowest published to date for the given surface dopant concentration, and is roughly an order of magnitude lower than values published in [8] and [9]. This result is extracted from three sets of TLM structures which were processed simultaneously. The measurements of resistance versus pad spacing for all three sets and the linear fit are presented in Fig. 6, and the extracted parameters presented in Table 1.



**Figure 4:** Contact resistivity for 600 W boat power, 120 s shutter delay. Sintering was performed at designated temperature for 30 minutes.



**Figure 5:** Contact resistivity for 800 W boat power, 60 s shutter delay. Sintering was performed at designated temperature for 30 minutes.



**Figure 6:** Resistance vs TLM pad separation for ‘As evaporated’ 800W deposition of Fig. 5 for different surface doping concentration,  $N_s$ . The fit is a linear fit but presented in a semi logarithmic scale to enable visibility of the intercept at  $x=0$ .

**Table 1:** Extracted TLM parameters for ‘As evaporated’ 800W deposition of Fig. 5.

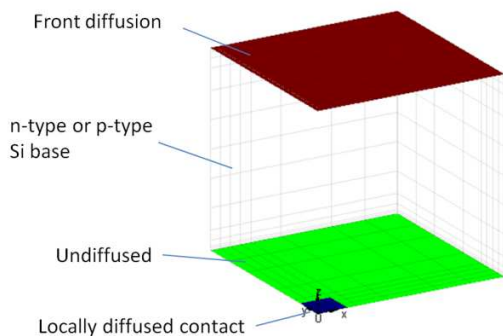
	Surface doping concentration ( $\text{cm}^{-3}$ )				
	$9.9 \times 10^{19}$	$5.2 \times 10^{19}$	$3.8 \times 10^{19}$	$2.4 \times 10^{19}$	$1.2 \times 10^{19}$
$R_{\text{sheet}} (\Omega/\square)$	19.5	30.6	45.6	75.9	157.1
$2 \cdot R_C (\Omega)$	0.015	0.033	0.040	0.103	0.597
$L_T (\mu\text{m})$	2.3	3.3	2.6	4.1	11.4
$\rho_C (\mu\Omega \cdot \text{cm}^2)$	1.04	3.31	3.16	12.75	204.2

#### IV. IMPLICATION TO CELL EFFICIENCY

Solar cell design always contains a trade-off relating to the contact area. Increasing the contact area introduces more recombination and shading losses (for front contact devices) whereas decreasing the contact area introduces greater resistive losses due to contact resistance and current crowding. Thus, the low contact resistivity presented above could lead to a reevaluation of the optimal contact area in high-efficiency cells. We demonstrate this optimisation and its ramifications for cell efficiency using 3D simulation with Quokka [12]. The unit cell used for this simulation as illustrated in Fig. 7 is an idealised structure with fully contacted but unshaded front emitter, with locally diffused rear point contact as is typical of Passivated Emitter Rear Locally Diffused (PERL) solar cells, and locally diffused Interdigitated Back Contact (IBC) cells. The bulk recombination is calculated using the intrinsic lifetime model for a bulk resistivity of  $100 \text{ } \Omega \cdot \text{cm}$  [13], substrate thickness of  $230 \text{ } \mu\text{m}$ , and a generation profile calculated using the AM1.5g spectrum with an optimised anti-reflection coating, yielding  $42 \text{ mA/cm}^2$  of photogeneration.

Since the simulation is designed with the intention of maximising the sensitivity to the contact recombination and resistive losses, all surfaces are regarded as ideal (zero recombination) except for the locally diffused contact region, and no bulk Shockley-Read-Hall (SRH) recombination is included.

The rear contact fraction is optimised for each combination of  $\rho_c$  and  $J_0$  in the simulation by fixing the dot size to  $20 \times 20 \text{ } \mu\text{m}$  squares and varying the pitch of the contact-to-contact spacing. The choice of the  $20 \times 20 \text{ } \mu\text{m}$  contact size is due to it being achievable by photolithography, laser processing [4], and within achievable range for high resolution ink-jet printing [14].



**Figure 7:** Geometry of the simulation unit cell, featuring a locally diffused rear point contact. Front refers to the illuminated side. The contact size is fixed at  $20 \times 20 \text{ } \mu\text{m}$ , and the unit cell dimensions in x- and y-direction are varied to find the optimum efficiency.

The simulation is performed for both  $100 \text{ } \Omega \cdot \text{cm}$  n-type and p-type wafers where the locally diffused contact is N+ doped and P+ doped respectively.

The bulk resistivity is high enough that it is essentially considered to be intrinsic silicon under operating conditions,

and therefore nullifies the differences of the diffused regions being either a back surface field (BSF, same doping polarity as the bulk Si), or emitter (opposite doping polarity to bulk Si). Therefore, the presented results for both n+ and p+ contacts applies irrespective of it being a BSF or emitter, which is particularly useful in its interpretation for IBC devices.

Results of the simulation are presented in Figs. 8 & 9, where the rainbow color contours represent the maximum efficiency found by optimization of the unit cell pitch. The resulting optimal pitch is also represented as an overlaid yellow/orange dotted line contour. Therefore, for any position within the x-y axis of the plot, there exist an optimal efficiency, and an optimal pitch used to achieve it. Such an approach to efficiency potential via multidimensional simulations of an idealised structure was similarly employed in [15, 16] using equivalent circuit models, and in [17, 18] with consideration of crowding effects.

The n+ contact results from this work are superimposed into Fig. 8, where the  $J_0$  values used for this region are obtained experimentally by photoconductance decay measurement on the samples prior to its preparation for TLM measurements. The results are compared to several passivated contacts [17-19]. The difference between highest efficiency attainable for Si/Al contact and passivated contacts are small, which fall within the efficiency range of 27.8 -28.2 %.

A similar observation is made for p+ contacts as presented in Fig. 9. The Si(p+)/Al contact data is from reference [6] and was performed using an identical process as described for Fig. 5 using 800 W deposition power, and  $230 \text{ } ^\circ\text{C}$  sintering in FGA. Results for Si(p+)/Al contacts at higher surface dopant concentration as plotted in Fig. 9 was extracted by combining measured  $J_0$  results from [20] and converting the measured surface doping concentration to contact resistivity by using a power fit to Schorder's data in [9]. Results of passivated contacts from literature [19, 21] are also superimposed over the contour plot. The best results for direct Si/Al contact and passivated contacts fall between 27.4 – 27.8 % efficiency.

In both Figs. 8 and 9 the efficiency contours plateau at a contact resistivity less than  $10^4 \text{ } \Omega \cdot \text{cm}^2$ , indicating that the resistive loss at the contact no longer limits the device efficiency. It is rather the internal bulk resistance and recombinative losses that dominate the losses.

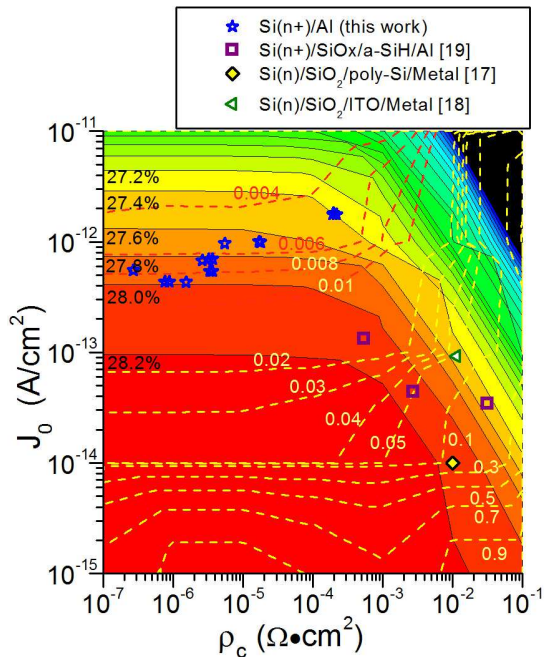
As was briefly noted above, this idealised simulation case highlights the differences between the contact properties. If realistic values of surface and bulk recombination are then included, it will further reduce the differences between optimal efficiency for the different contact technologies.

By comparing the data points of different contact technologies on the same plot, we are assuming negligible difference in optical performance of the different rear contact stacks. This is a reasonable approximation since intermediate layers on most passivated contact stacks are very thin and weakly absorbing to long wavelength light.

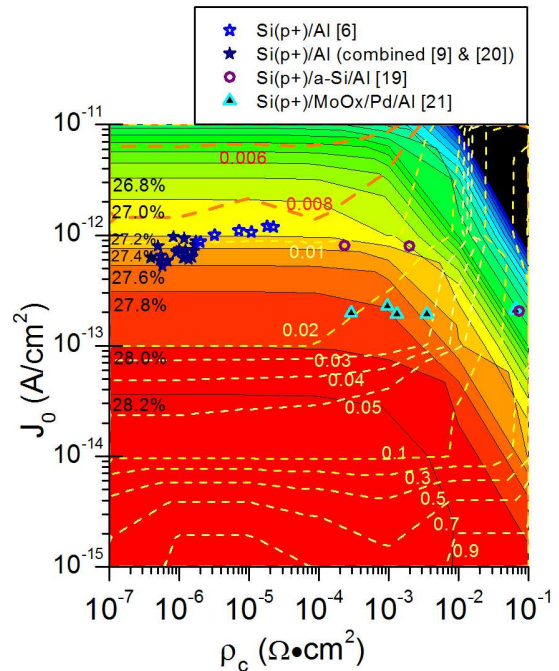
Unless a self-aligned technique is used for diffusion and contact opening, perfect alignment such as is assumed for the simulation is impossible. A fabricated device would require the contact opening to be smaller than the diffused region by an amount reasonable to the alignment tolerance of the tool used. To interpret Figs. 8 and 9 for a device fabricated with contact opening smaller than the diffused region (such as is



done in [6]), then the worst case assumption is to assume the unpassivated  $J_0$  for the entire diffused area, and an increase in the contact resistivity by the ratio of contact:diffused area. This would result in data points being shifted towards the right side of the contour plot. For both the n+ and p+ contacts, the contact resistivity for heavily diffused Si/Al contacts is sufficiently low that an increase by a factor of 2 in contact resistivity will not decrease its optimal efficiency.



**Figure 8:** Optimal efficiency for rear locally diffused n+ contacts as would be the case for IBC or n-type PERL. The rainbow colored contour plot is efficiency and the yellow/orange dotted line is the optimal contact fraction to achieve it (eg: 0.01 representing 1% rear contact area).



**Figure 9:** Optimal efficiency for rear locally diffused p+ contacts as would be the case for an IBC or p-type PERL cells. The rainbow colored contour plot is the efficiency and the yellow/orange dotted line is the optimal contact fraction to achieve it (eg: 0.01 representing 1% rear contact area).

## V. CONCLUSION

The results presented in Table 1 for Al contact resistivity on phosphorus doped Si are the lowest values presented to date at their respective doping concentration, and we demonstrated that very low contact resistance is achieved without the need of a sintering step.

The obtained results are compared to passivated contact technology via 3D simulation of an ideal unit cell with locally diffused contacts. The conclusion from these simulations is that direct Si/Al contacts and the best published results for passivated contacts (amorphous Si for n+ and Molybdenum oxide contacts for p+) appear to have efficiency above 27.4%. Therefore, for a practical device of ~25% efficiency, these contact techniques will not be the limiting factor at optimal contact fractions.

From a fabrication practicality point of view, in order to take advantage of the very low contact resistivity achievable via evaporated Al, advanced techniques which provide fine features with precise alignment are required. Such limitations are not fundamental limits and can be alleviated by advancement in technology such as adoption of high resolution ink-jet printing or laser patterning / doping.

## REFERENCES

- [1] A. Cuevas, P. A. Basore, G. Giroult-Matlakowski, and C. Dubois, "Surface recombination velocity of highly doped n-type silicon," *Journal of Applied Physics*, vol. 80, pp. 3370-3375, 1996.

- [2] G. A. Armin, *Crystalline Silicon Solar Cells: Advanced Surface Passivation and Analysis*. Sydney: Centre for Photovoltaic Engineering, University of New South Wales, Sydney, Australia, 1999.
- [3] A. Wang, J. Zhao, and M. A. Green, "24% efficient silicon solar cells," *Applied Physics Letters*, vol. 57, pp. 602-604, 1990.
- [4] A. W. Blakers, A. Wang, A. M. Milne, J. Zhao, and M. A. Green, "22.8% efficient silicon solar cell," *Applied Physics Letters*, vol. 55, pp. 1363-1365, 1989.
- [5] J. Zhao, A. Wang, P. Altermatt, and M. A. Green, "Twenty-four percent efficient silicon solar cells with double layer antireflection coatings and reduced resistance loss," *Applied Physics Letters*, vol. 66, pp. 3636-3638, 1995.
- [6] E. Franklin, K. Fong, K. McIntosh, A. Fell, A. Blakers, T. Kho, D. Walter, D. Wang, N. Zin, M. Stocks, E.-C. Wang, N. Grant, Y. Wan, Y. Yang, X. Zhang, Z. Feng, and P. J. Verlinden, "Design, fabrication and characterisation of a 24.4% efficient interdigitated back contact solar cell," *Progress in Photovoltaics: Research and Applications*, pp. n/a-n/a, 2014.
- [7] F. Heinemeyer, C. Mader, D. Münster, T. Dullweber, and R. Brendel, "Inline high-rate thermal evaporation of aluminium for novel industrial solar cell metallization," *25<sup>th</sup> EU PVSEC Valencia*, pp. 2066-8, 2010.
- [8] A. Y. C. Yu, "Electron tunneling and contact resistance of metal-silicon contact barriers," *Solid-State Electronics*, vol. 13, pp. 239-247, 1970.
- [9] D. K. Schroder and D. L. Meier, "Solar cell contact resistance; A review," *Electron Devices, IEEE Transactions on*, vol. 31, pp. 637-647, 1984.
- [10] K. C. Fong, "Fabrication and characterisation of elongate solar cells," PhD Thesis, The Australian National University, Canberra, 2012.
- [11] H. H. Berger, "Contact resistance and contact resistivity," *Journal of The Electrochemical Society*, vol. 119, pp. 507-514, 1972.
- [12] A. Fell, "A free and fast three-dimensional/two-dimensional solar cell simulator featuring conductive boundary and quasi-neutrality approximations," *Electron Devices, IEEE Transactions on*, vol. 60, pp. 733-738, 2013.
- [13] A. Richter, F. Werner, A. Cuevas, J. Schmidt, and S. W. Glunz, "Improved parameterization of Auger recombination in silicon," *Energy Procedia*, vol. 27, pp. 88-94, 2012.
- [14] L. Zhongtian, C. Ran, Y. Yu, Z. Wei, W. Xi, I. Perez-Wurfl, and A. Lennon, "Patterning and metallization of silicon solar cells by inkjet-printed functional ink on a photoresist layer," in *Photovoltaic Specialist Conference (PVSC), 2014 IEEE 40th*, 2014, pp. 2499-2501.
- [15] A. Fell, S. Surve, E. Franklin, and K. J. Weber, "Characterization of laser-doped localized p-n junctions for high efficiency silicon solar cells," *Electron Devices, IEEE Transactions on*, vol. 61, pp. 1943-1949, 2014.
- [16] J. Bullock, D. Yan, and A. Cuevas, "Passivation of aluminium-n<sup>+</sup> silicon contacts for solar cells by ultrathin Al<sub>2</sub>O<sub>3</sub> and SiO<sub>2</sub> dielectric layers," *Physica Status Solidi (RRL) – Rapid Research Letters*, vol. 7, pp. 946-949, 2013.
- [17] F. Feldmann, M. Bivour, C. Reichel, M. Hermle, and S. W. Glunz, "Passivated rear contacts for high-efficiency n-type Si solar cells providing high interface passivation quality and excellent transport characteristics," *Solar Energy Materials and Solar Cells*, vol. 120, Part A, pp. 270-274, 2014.
- [18] D. L. Young, W. Nemeth, S. Grover, A. Norman, H.-C. Yuan, B. G. Lee, V. LaSalvia, and P. Stradins, "Carrier selective, passivated contacts for high efficiency silicon solar cells based on transparent conducting oxides," *Energy Procedia*, vol. 55, pp. 733-740, 2014.
- [19] J. Bullock, A. Cuevas, D. Yan, B. Demareux, A. Hessler-Wyser, and S. De Wolf, "Amorphous silicon enhanced metal-insulator-semiconductor contacts for silicon solar cells," *Journal of Applied Physics*, vol. 116, pp. -, 2014.
- [20] D. Yan and A. Cuevas, "Empirical determination of the energy band gap narrowing in p<sup>+</sup> silicon heavily doped with boron," *Journal of Applied Physics*, vol. 116, pp. -, 2014.
- [21] J. Bullock, A. Cuevas, T. Allen, and C. Battaglia, "Molybdenum oxide MoO<sub>x</sub>: A versatile hole contact for silicon solar cells," *Applied Physics Letters*, vol. 105, pp. -, 2014.



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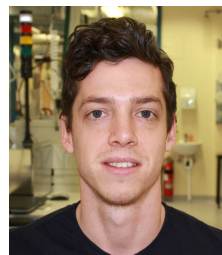
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